## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

Hada et al.

Appl. No.

: 10/535,533

Filed

: May 19, 2005

For

METHOD OF FORMING RESIST

PATTER, POSITIVE RESIST

COMPOSITION, AND LAYERED

**PRODUCT** 

Examiner

Chu, John S. Y.

Group Art Unit

1752

## **RESPONSE TO OFFICE ACTION**

## Mail Stop Amendment

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed March 9, 2007, please consider the following remarks

Remarks begin on page 2 of this paper.